

# MNC 2014 (November 4-7, Hilton Fukuoka Sea Hawk, Fukuoka, Japan) Schedule

## Tuesday, November 4

Room A (Rigel, 3F)
13:00-16:10 MNC 2014 Technical Seminar in Japanese
Seala Brasserie and Lounge (4F)
17:30-19:30 Get Together Party

Technical Seminar in Japanese Registration Desk  
November 4, 12:20 - 15:00 (1F Lobby)

Conference Registration Desk  
November 4, 15:30 - 18:30 (1F Lobby)  
November 5, 8:30 - 12:10 (1F Lobby)  
November 5, 12:20 - 18:00 (3F Lobby)  
November 6, 8:30 - 18:00 (3F Lobby)  
November 7, 8:30 - 16:00 (3F Lobby)

## Wednesday, November 5

Room P-1 (Argos A, 1F)
5P-1: Opening & Plenary Session 9:30-12:10 Opening Remark and 2014 Award Presentation T. Mayer, Pennsylvania State Univ., USA J. Hone, Columbia Univ., USA K. Kataoka Univ. of Tokyo, Japan
Lunch

Room A (Vega, 3F)	Room B (Rigel, 3F)	Room C (Chapel, 3F)	Room D (Boardroom, 3F)
5A-2: 13:30-15:10 Electron and Ion Beam Technologies	5B-2: 13:30-15:20 Inorganic Nanomaterials I	5C-2: 13:30-15:00 Nanofabrication I	5D-2: 13:30-15:10 Symp. B: Hybrid Nanosystem I
5A-2 Author's Interview: 15:10-15:20	5B-2 Author's Interview: 15:20-15:30	5C-2 Author's Interview: 15:00-15:10	
Garden Lobby (3F)			
Coffee Break			
5A-3: 15:25-16:55 Symp. A: Advanced Patterning I	5B-3: 15:30-17:20 BioMEMS, Lab on a Chip I	5C-3: 15:25-17:05 Innovative Microdevices	5D-3: 15:25-17:05 Symp. B: Hybrid Nanosystem II
5A-3 Author's Interview: 16:55-17:05	5B-3 Author's Interview: 17:20-17:30	5C-3 Author's Interview: 17:05-17:15	5D-3 Author's Interview: 17:05-17:15
Vega (3F) and Garden Lobby (3F)			
17:30-19:00 Happy Hour			

## Thursday, November 6

Room A (Vega, 3F)	Room B (Rigel, 3F)	Room C (Chapel, 3F)	Room D (Boardroom, 3F)
6A-4: 9:00-10:30 Advanced Photolithography	6B-4: 9:00-10:30 Nanostructure Engineered Devices	6C-4: 9:00-10:30 Process and Characterization I	6D-4: 9:00-10:30 Graphene Application
6A-4 Author's Interview: 10:30-10:40			
Garden Lobby (3F)			
Coffee Break			
6A-5: 10:45-12:15 Symp. A: Advanced Patterning II	6B-5: 10:40-12:10 Optoelectric Devices and Materials	6C-5: 10:35-12:15 Process and Characterization II	6D-5: 10:35-12:15 Nanocarbon Property
6A-5 Author's Interview: 12:15-12:25	6B-4,5 Author's Interview: 12:10-12:25	6C-4, 5 Author's Interview: 12:15-12:25	6D-4,5 Author's Interview: 12:15-12:25
Lunch			
6A-6: 13:40-15:30 Nanofabrication II	6B-6: 13:40-15:20 Inorganic Nanomaterials II	6C-6: 13:20-15:30 Nano Tool	6D-6: 13:20-15:30 BioMEMS, Lab on a Chip II
6A-6 Author's Interview: 15:30-15:40	6B-6 Author's Interview: 15:20-15:30	6C-6 Author's Interview: 15:30-15:40	6D-6 Author's Interview: 15:30-15:40
Garden Lobby (3F)			
Coffee Break			
Room P-2 (Argos D, 1F)			
6P-7: 15:40-17:40 Poster Session I Advanced Photolithography, Electron and Ion Beam Technologies, Nanocarbons, Nanofabrication, Inorganic Nanomaterials, BioMEMS, Lab on a Chip and Microsystem Technology and MEMS			
Penthouse (34F)			
18:00-20:00 Banquet			

## Friday, November 7

Room A (VEGA, 3F)	Room B (Rigel, 3F)	Room C (Chapel, 3F)	Room D (Boardroom, 3F)
7A-8: 9:00-10:00 Symp. A: Advanced Patterning III	7B-8: 9:00-10:20 Organic Nanomaterials	7C-8: 9:00-10:20 Nanofabrication III	7D-8: 9:00-10:30 Nanotube Application
	7B-8 Author's Interview: 10:20-10:30	7C-8 Author's Interview: 10:20-10:30	
Garden Lobby (3F)			
Coffee Break			
Room A (Vega, 3F)	Room B (Rigel, 3F)	Room C (Chapel, 3F)	Room D (Boardroom, 3F)
7A-9: 10:15-11:45 Symp. A: Advanced Patterning IV	7B-9: 10:45-11:55 Nanoimprint, Nanoprint and Rising Lithography I	7C-9: 10:45-11:45 Nanoscale Memory	7D-9: 10:45-12:05 Transition Metal Dichalcogenides
7A-8, 9 Author's Interview: 11:45-11:55	7B-9 Author's Interview: 11:55-12:05	7C-9 Author's Interview: 11:45-11:55	7D-8, 9 Author's Interview: 12:05-12:15
Lunch			
7A-10: 13:00-14:30 Resist and Directed Self-Assembly	7B-10: 13:00-14:30 Nanoimprint, Nanoprint and Rising Lithography II	7C-10: 13:10-14:30 Sensing Devices	7D-10: 13:10-14:30 Inorganic Nanomaterials III
7A-10 Author's Interview: 14:30-14:40	7B-10 Author's Interview: 14:30-14:40	7C-10 Author's Interview: 14:30-14:40	7D-10 Author's Interview: 14:30-14:40
Room P-2 (Argos D, 1F)			
7P-11: 14:40-16:40 Poster Session II Symp. B: Hybrid Nanosystem, Resist and Directed Self-Assembly, Nanocarbons, Nanodevices, Nanofabrication, Inorganic Nanomaterials, Organic Nanomaterials, NanoTool and Nanoimprint, Nanoprint and Rising Lithography			